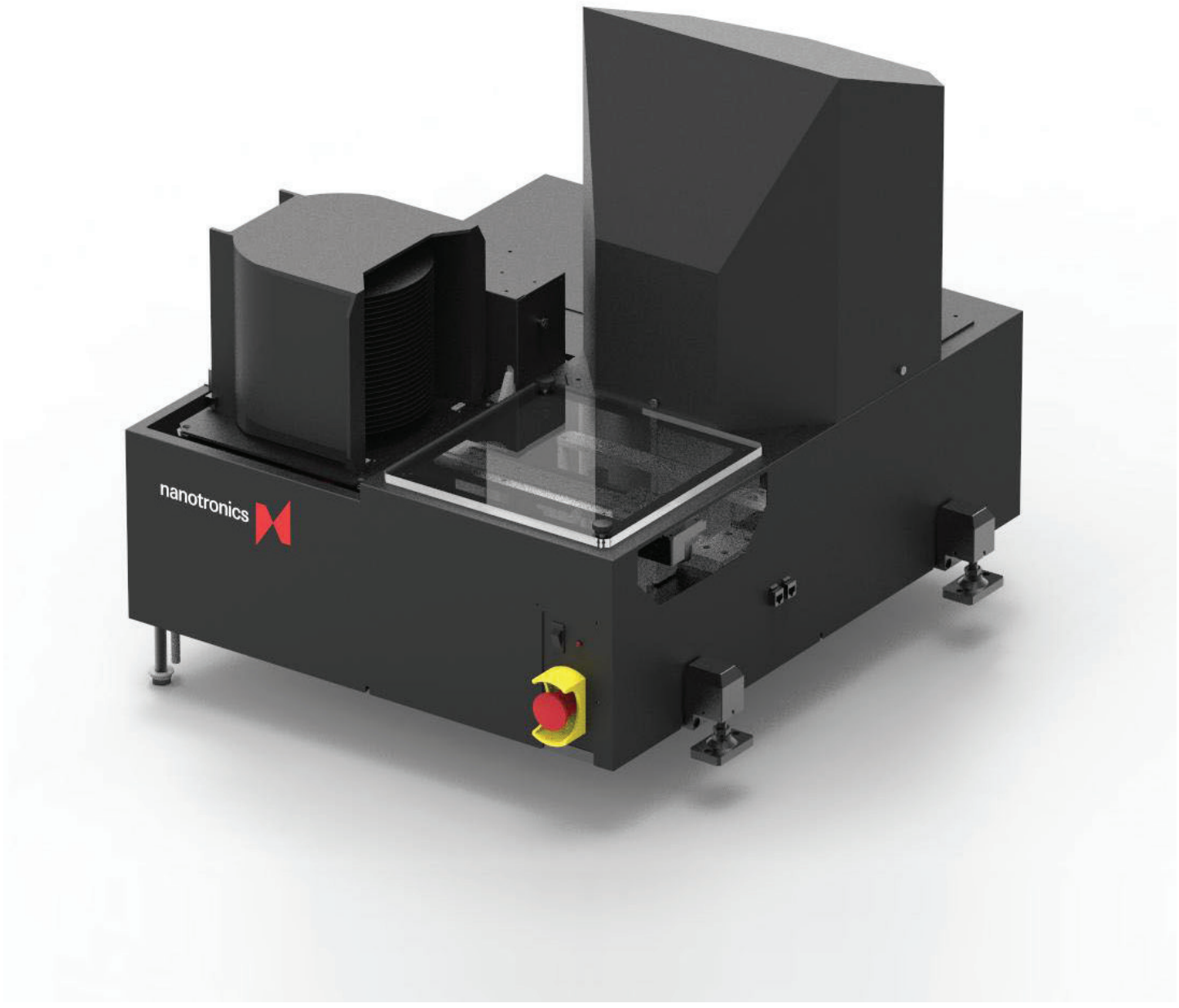
nSpec® Macro



Rapid Automated Macro Inspection

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nanotronics

nSpec® Macro

No matter your specific wafer inspection requirements, Nanotronics provides a range of solutions for obtaining rapid results.

This compact system is designed for high-throughput macro inspection for wafers up to 200 mm. In milliseconds, the nSpec® Macro automatically detects and quantifies numerous defects from 50 to 100 microns, contingent on field of view or wafer size.

nSpec® Macro allows one to illuminate the full circumference of the specimen, or to program lighting angles and/or discrete lighting vectors. Brightfield, Darkfield, Orthogonal, and configurable Oblique Lighting angles paired with individually modifiable LEDs adjust the intensity, color, and location of illumination.

The system automatically exports a csv file and is SECS/GEM compatible, or can be tailored to fit customer requirements.

Automated Wafer Handling

All Nanotronics Automation nSpec® Macros incorporate a wafer loader that meets industry-standard demands.

Nanotronics creates end effectors that load whole individual wafers and/or wafers with exclusion zones. Each end effector is conceived according to the customer's needs.

Wafer Loader

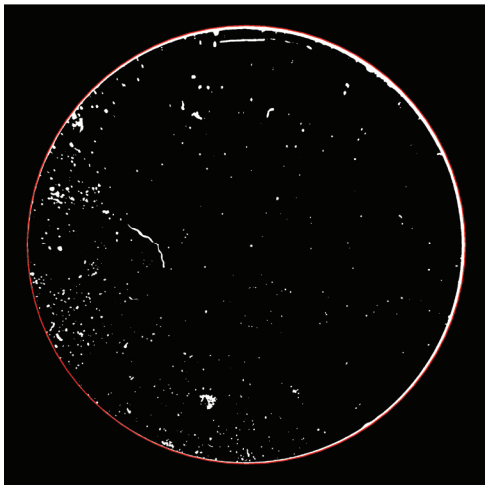
Runs one cassette at a time	Standard h-bar cassette
Standard Wafer Sizes	50, 75, 100, 150, or 200 mm
Dimension (W x D x H)	71 cm x 74 cm x 67 cm
Weight	62 kg
Minimum Vacuum Requirement	20 in. Hg
Power supply	220v, 3.5 amps

Control Software

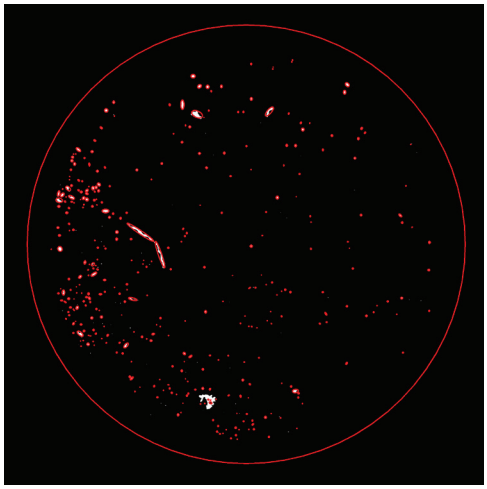
Recipes are easy to configure and save as needs evolve. Multiple scans can be run sequentially with complete flexibility in illumination angle, intensity, and wavelength.

Optics

- **Darkfield Illumination Mode**
  Angle of illumination: 0 degrees
- **Oblique Illumination Mode**
  Angle of illumination: 0 to 80 degrees
- **Brightfield Illumination Mode**
  Angle of illumination: 90 degrees
- **Orthogonal Illumination Mode**
  Angle of illumination: 90 degrees (through the lens)



Sample Scan



Annotated Darkfield Macro Scan